

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1-36. (Canceled)

37. (Currently Amended) An optical element to be used for an exposure apparatus configured to illuminate a mask with an exposure light beam for transferring a pattern on the mask onto a substrate through a projection optical system and to interpose a given liquid in a space between a surface of the substrate and the projection optical system, the optical element comprising:

a transmissive base material having a first surface on which the exposure light beam enters into the transmissive base material, a second surface on which the exposure light beam exits from the transmissive base material, and a side surface of the transmissive base material,
and

a light-shielding film provided on ~~a~~the side surface of ~~a~~the transmissive optical element ~~base material~~ on ~~a substrate~~the substrate's side of the projection optical system.

38. (Original) The optical element according to claim 37,
wherein the light-shielding film is formed of any of a metal film and a metal oxide film.

39. (Original) The optical element according to claim 38,
wherein the metal film is made of at least one selected from the group consisting of Au, Pt, Ag, Ni, Ta, W, Pd, Mo, Ti, and Cr, and
the metal oxide film is made of at least one selected from the group consisting of ZrO₂, HfO₂, TiO₂, Ta₂O₅, SiO, and Cr₂O₃.

40-59. (Canceled)

60. (Currently Amended) An exposure apparatus configured to illuminate a mask with an exposure light beam for transferring a pattern on the mask onto a substrate through a projection optical system, and to interpose a given liquid in a space between a surface of the substrate and the projection optical system, the exposure apparatus comprising:

a transmissive base material having a first surface on which the exposure light beam enters into the transmissive base material, a second surface on which the exposure light beam exits from the transmissive base material, and a side surface of the transmissive base material,
and

a light-shielding film provided on a the side surface of a the transmissive optical element base material on a substrate the substrate's side of the projection optical system.

61. (Original) The exposure apparatus according to claim 60,
wherein the light-shielding film is formed of any of a metal film and a metal oxide film.

62. (Original) The exposure apparatus according to claim 61,
wherein the metal film is made of at least one selected from the group consisting of Au, Pt, Ag, Ni, Ta, W, Pd, Mo, Ti, and Cr, and
the metal oxide film is made of at least one selected from the group consisting of ZrO_2 , HfO_2 , TiO_2 , Ta_2O_5 , SiO , and Cr_2O_3 .

63. (Previously Presented) The optical element according to claim 37,
wherein the light-shielding film prevents irradiation of the exposure light beam onto a sealing member.

64. (New) The optical element according to claim 37,
wherein the second surface of the transmissive base material contacts the given liquid while the mask is illuminated with the exposure light beam.

65. (New) The exposure apparatus according to claim 60,

wherein the second surface of the transmissive base material contacts the given liquid while the mask is illuminated with the exposure light beam.

66. (New) The exposure apparatus according to claim 60, further comprising:
a sealing member which prevents leakage of the given liquid,
wherein the light-shielding film is provided between the transmissive base material of the optical element and the sealing member.